

MNC 2016 (November 8-11, ANA Crowne Plaza Kyoto, Kyoto, Japan) Schedule

Tuesday, November 8

Room B (Suzaku 2, 2F)
13:10-17:05 MNC 2016 Technical Seminar in Japanese
Room P (Heian 1, 2F)
17:25-19:25 Get Together Party

Technical Seminar in Japanese Registration Desk
November 8, 12:30 - 16:00 (2F Lobby in front of Room B)

Conference Registration Desk
November 8, 12:30 - 18:30 (2F Lobby in front of Room B)
November 9, 8:30 - 18:00 (2F Lobby in front of Room A)
November 10, 8:30 - 18:20 (2F Lobby in front of Room A)
November 11, 8:30 - 16:20 (2F Lobby in front of Room A)

Wednesday, November 9

Room A (Heian 4, 2F)			
9P-1: Opening & Plenary Session 9:30-12:10			
<i>Lunch</i>			
Room A (Heian 4, 2F)	Room B (Suzaku 2, 2F)	Room C (Suzaku 1, 2F)	Room D (Daigo, 2F)
9A-2: 13:30-15:10 Nanocarbon Properties I	9B-2: 13:30-15:20 Organic Nanomaterials 9B-2 Author's Interview: 15:20-15:30	9C-2: 13:30-15:20 NanoTool I	9D-2: 13:30-15:10 Symposium D: Innovation from Open Facilities I
Room P (Heian 1,2,3, 2F)			
<i>Coffee Break</i>			
9A-3: 15:25-17:05 Nanocarbon Growth	9B-3: 15:35-17:25 Electron and Ion Beam Technologies	9C-3: 15:35-16:55 NanoTool II	9D-3: 15:25-17:05 Symposium D: Innovation from Open Facilities II
9A-2, 3 Author's Interview: 17:05-17:15	9B-3 Author's Interview: 17:25-17:35	9C-2, 3 Author's Interview: 16:55-17:05	9D-2, 3 Author's Interview: 17:05-17:15
Room A (Heian 4, 2F) and Room P (Heian 1,2,3, 2F)			
17:35-19:00 Happy Hour			

Thursday, November 10

Room A (Heian 4, 2F)	Room B (Suzaku 2, 2F)	Room C (Suzaku 1, 2F)	Room D (Daigo, 2F)
10A-4: 9:00-10:30 Symposium C: Nanosensors and Their Promises for IoT Society I	10B-4: 9:00-10:20 Nanocarbon Properties II	10C-4: 9:00-10:30 Nanofabrication I 10C-4 Author's Interview: 10:30-10:40	10D-4: 9:00-10:30 Microsystem Technology & MEMS I
Room P (Heian 1,2,3, 2F)			
<i>Coffee Break</i>			
10A-5: 10:45-11:45 Symposium C: Nanosensors and Their Promises for IoT Society II	10B-5: 10:35-12:35 Nanocarbon Application 10B-4, 5 Author's Interview: 12:35-12:45	10C-5: 10:55-12:25 Nanofabrication II 10C-5 Author's Interview: 12:25-12:35	10D-5: 10:45-12:05 Microsystem Technology & MEMS II 10D-4, 5 Author's Interview: 12:05-12:15
<i>Lunch</i>			
10A-6: 14:10-16:10 Symposium B: Forefront of Graphene & Related 2D Materials	10B-6: 14:10-15:30 Inorganic Nanomaterials I 10B-6 Author's Interview: 15:30-15:40	10C-6: 14:10-16:00 Nanofabrication III 10C-6 Author's Interview: 16:00-16:10	10D-6: 13:40-16:00 Nanoimprint, Nanoprint and Rising Lithography 10D-6 Author's Interview: 16:00-16:10
Room P (Heian 1,2,3, 2F)			
<i>Coffee Break</i>			
Room P (Heian 1,2,3, 2F)			
10P-7: 16:10-18:10 Poster Session I Electron and Ion Beam Technologies, Nanocarbons, Nanodevices, Nanofabrication, Inorganic Nanomaterials, Organic Nanomaterials, NanoTool, Nanoimprint, Nanoprint and Rising Lithography, BioMEMS, Lab on a Chip and Microsystem Technology and MEMS			
Room A (Heian 3,4, 2F)			
18:20-20:20 Banquet			

Friday, November 11

Room A (Heian 4, 2F)	Room B (Suzaku 2, 2F)	Room C (Suzaku 1, 2F)	Room D (Daigo, 2F)
11A-8: 9:00-11:00 Symposium A: Metrology and Inspection for Advanced Patterning	11B-8: 9:00-10:30 Inorganic Nanomaterials II	11C-8: 9:00-10:30 Nano Resistive and Atomic Switching Devices	11D-8: 9:00-10:30 BioMEMS, Lab on a Chip I
Room P (Heian 1,2,3, 2F)			
<i>Coffee Break</i>			
11A-9: 11:15-12:25 Advanced Photolithography 11A-9 Author's Interview: 12:25-12:35	11B-9: 10:45-11:55 Inorganic Nanomaterials III 11B-8,9 Author's Interview: 11:55-12:05	11C-9: 10:45-12:05 Nanosensor Devices 11C-8,9 Author's Interview: 12:05-12:15	11D-9: 10:45-11:55 BioMEMS, Lab on a Chip II 11D-8, 9 Author's Interview: 11:55-12:05
<i>Lunch</i>			
11A-10: 14:00-15:10 Resist and Directed Self-Assembly 11A-10 Author's Interview: 15:10-15:20	11B-10: 13:30-15:10 Inorganic Nanomaterials IV 11B-10 Author's Interview: 15:10-15:20	11C-10: 13:30-15:10 Nano Devices 11C-10 Author's Interview: 15:10-15:20	11D-10: 13:30-15:10 Microsystem Technology and MEMS III 11D-10 Author's Interview: 15:10-15:20
Room P (Heian 1,2,3, 2F)			
11P-11: 15:20-17:20 Poster Session II Advanced Photolithography, Resist and Directed Self-Assembly, Nanocarbons, Nanodevices, Nanofabrication, Inorganic Nanomaterials, Nanoimprint, Nanoprint and Rising Lithography, BioMEMS, Lab on a Chip and Microsystem Technology and MEMS			